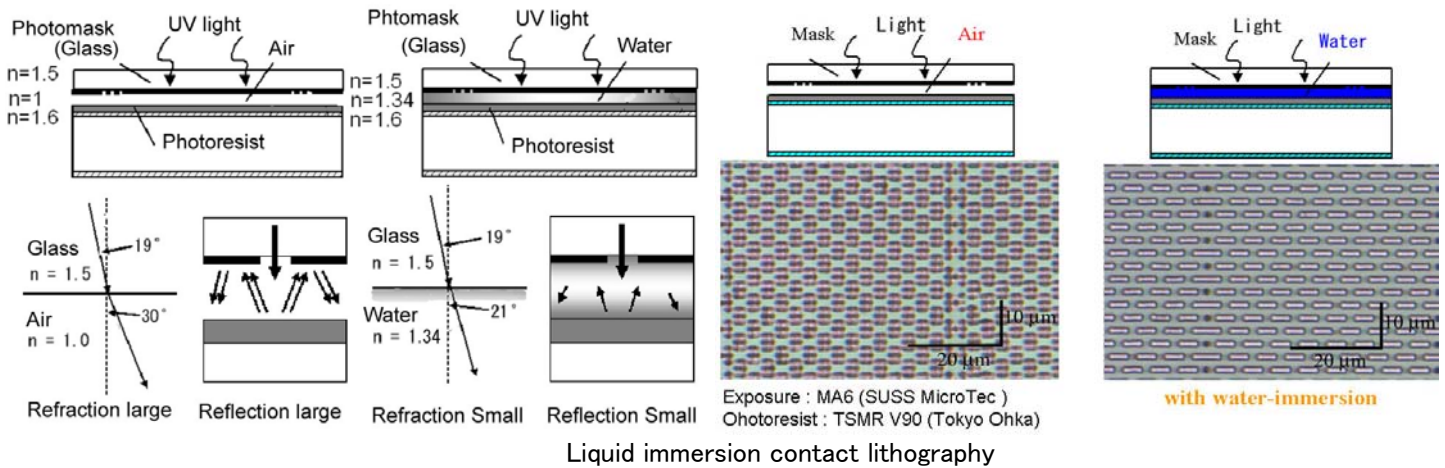
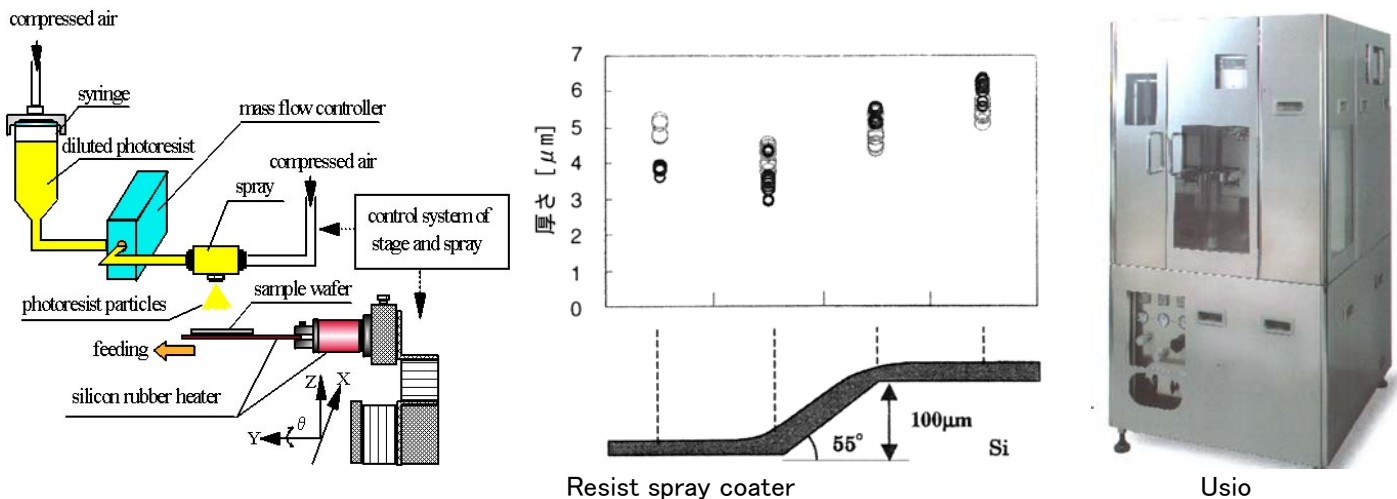


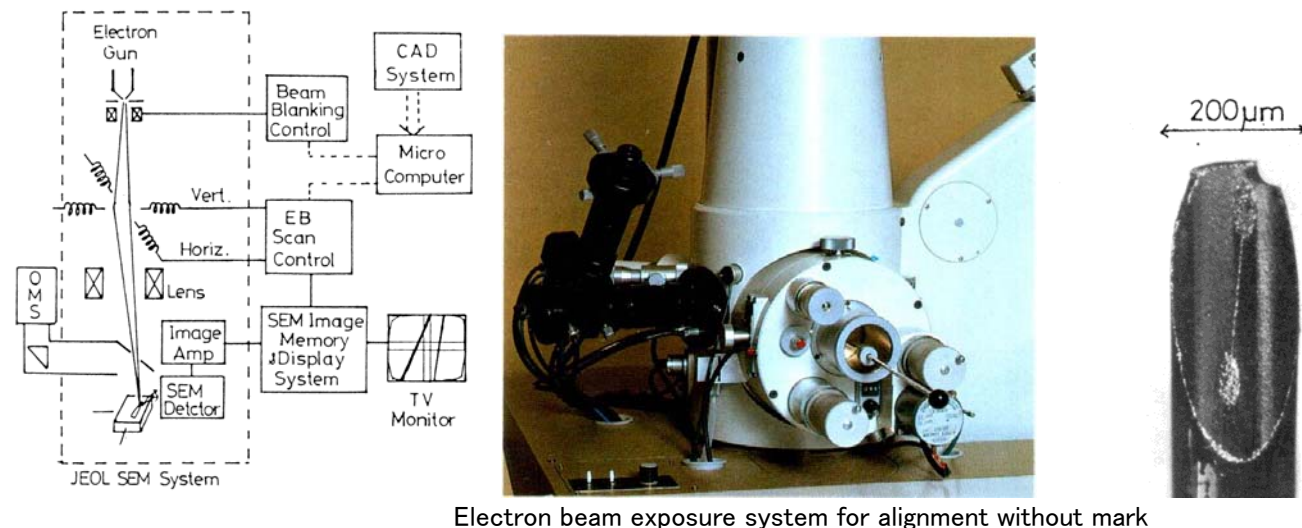
Patterning



Reference : K.-S.Chang, S.Tanaka and M.Esashi, A Micro-Fuel Processor with Trench-Refilled Thick Silicon Dioxide for Thermal Isolation Fabricated by Water-immersion Contact Photolithography, J. of Micromech. Microeng., 15 (2005) pp.S171-S178



Reference : V.K.Singh, M.Sasaki, K.Hane and M.Esashi, Flow Condition in Resist Spray Coating and Patterning Performance for Three-Dimensional Photolithography over Deep Structures, Jpn. J. Appl. Phys., 43 (2004) pp.2387-2391



Reference : S.Shoji, M.Esashi and T.Matsuo, A New Three-Dimensional Lithographic Technique and its Applications to the Fabrication of Micro Probe Sensors, Digest of Technical Papers, The 4th Int. Conf.on Solid State Sensors and Actuators (1987) pp.91-94